

Substitute for forms 1449A/PTO & 1449B/PTO

**FIRST INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**ATTORNEY'S DKT NO.
007413-060APPLICATION NO.
10/631,900APPLICANT
Wilfried CLAUSSFILING DATE
August 1, 2003GROUP
Unassigned**U.S. PATENT DOCUMENTS**

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Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
	X. ZHU et al., "Comprehensive Analysis of Electron Optical Design of SCALPEL-HT/Alpha", Proc. SPIE, Vol. 3997, pp. 170-183, July 2000, Emerging Lithographic Technologies IV, Elizabeth A. Dobbs, Ed.
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3-31-2004

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